FIG. 1

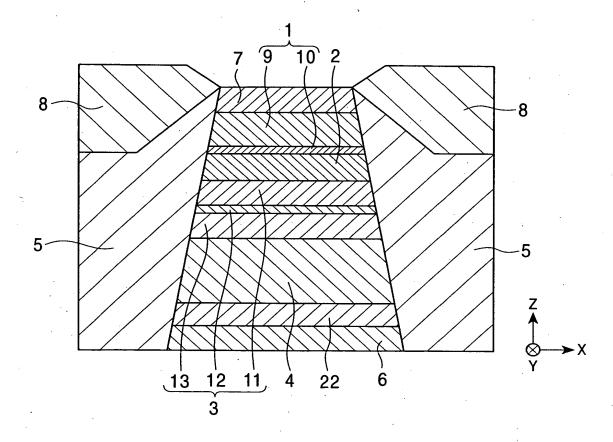


FIG. 2

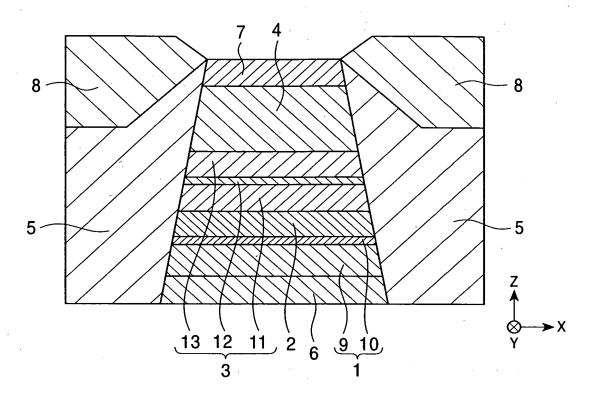


FIG. 3

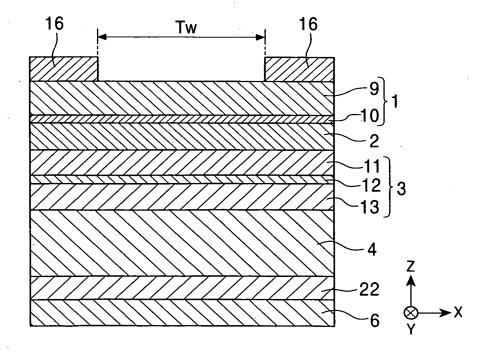


FIG. 4

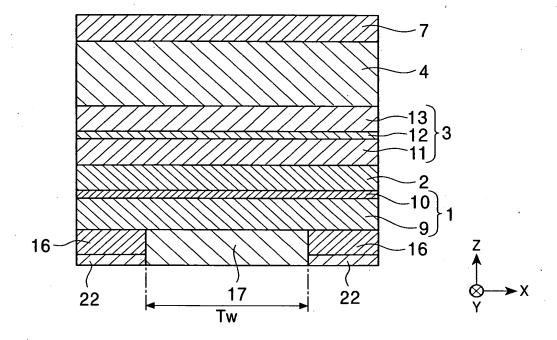


FIG. 5

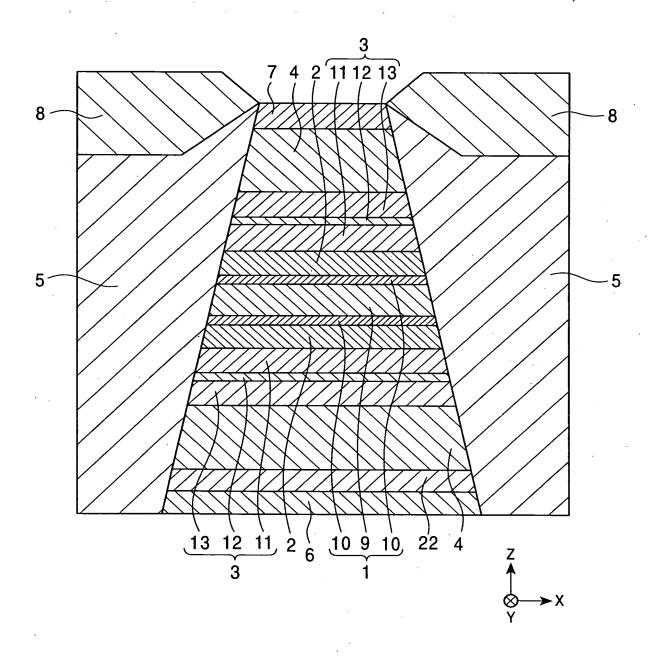


FIG. 6

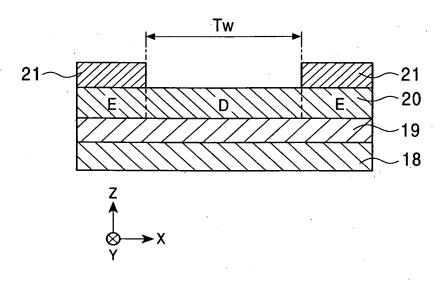


FIG. 7

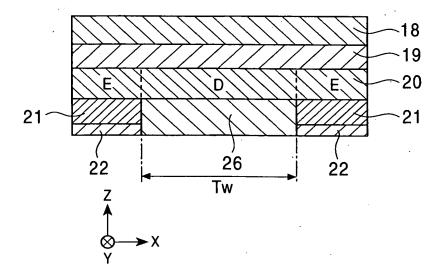
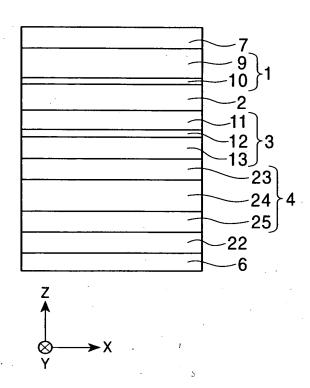
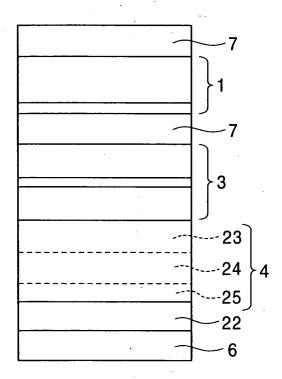


FIG. 8

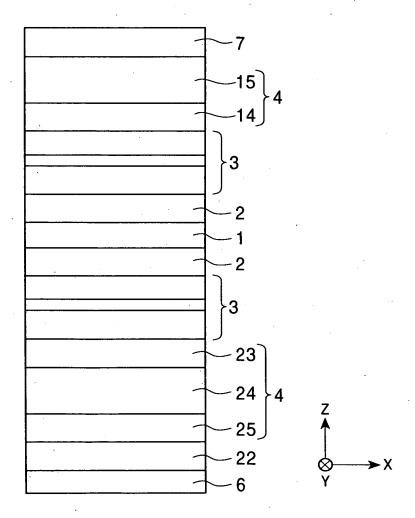
TDEDTA SECTORI





TDEOTO SECUERA

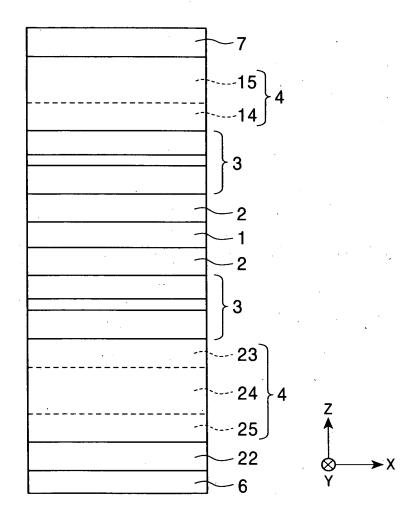
FIG. 10



he Same



FIG. 11



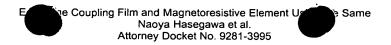


FIG. 12

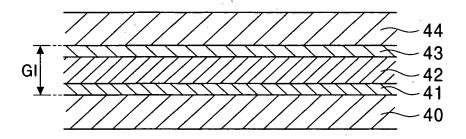
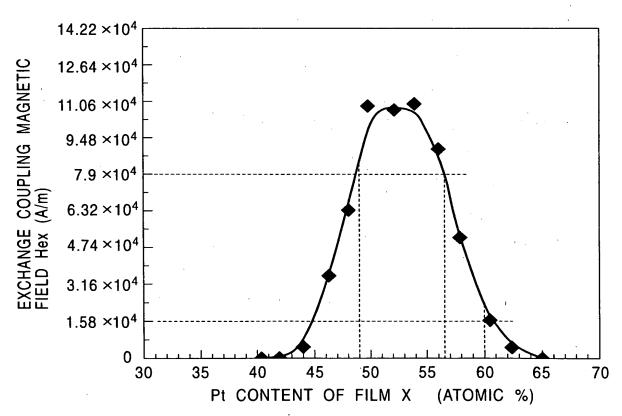


FIG. 13



FILM STRUCTURE: Si SUBSTRATE/ALUMINA/Ta(3nm)/NiFe (3nm)/PtMn(15nm)/Co (1.5nm)/Ru(0.8nm)/Co

(2.5nm)/Cu(2.3nm)/Co

(1nm)/NiFe(3nm)/Cu(1.5nm)/Ta(3nm)

Same

FIG. 14

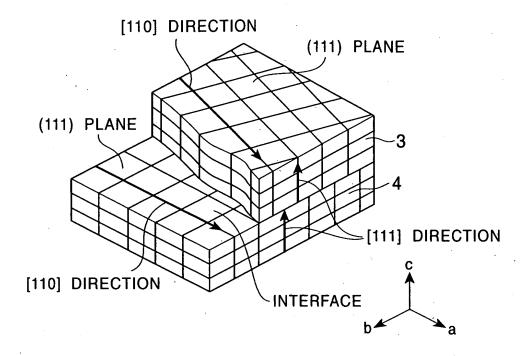


FIG. 15

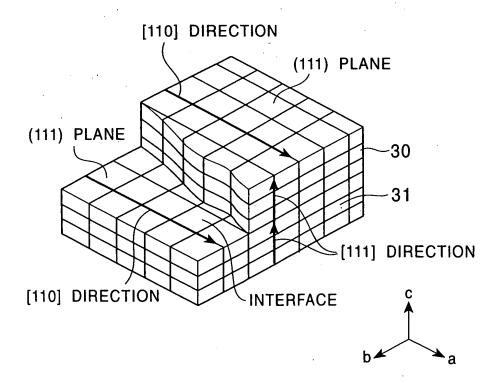
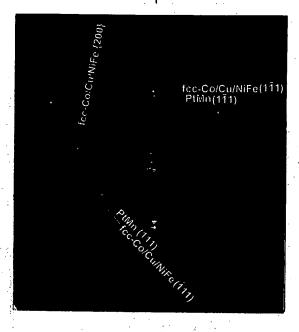


FIG. 16

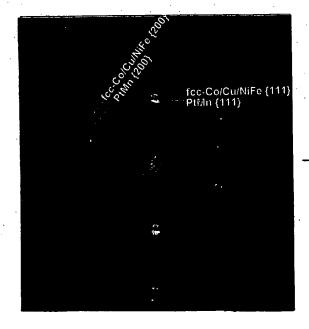
THICKNESS DIRECTION



FILM PLANE (TRANSVERSE) DIRECTION

FIG. 17

THICKNESS DIRECTION



→ FILM PLANE (TRANSVERSE) DIRECTION

FIG. 18

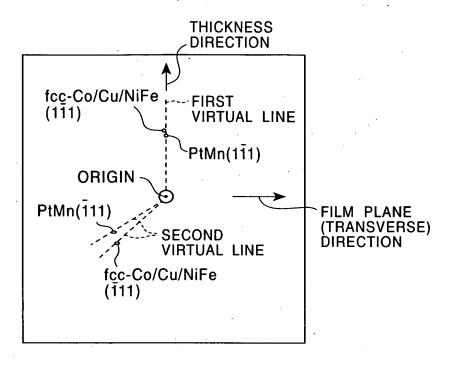
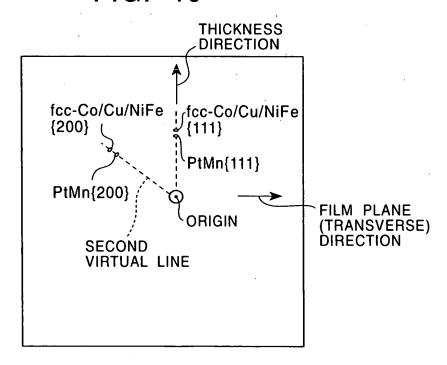


FIG. 19



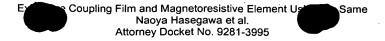


FIG. 20

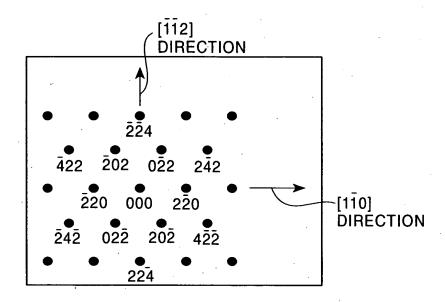


FIG. 21

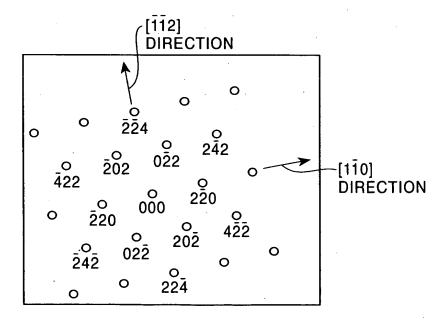


FIG. 22

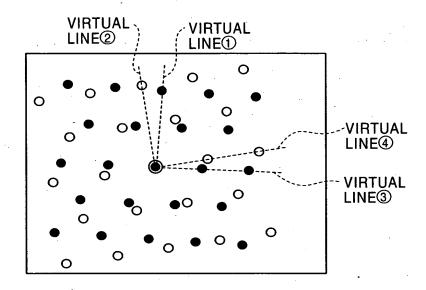


FIG. 23

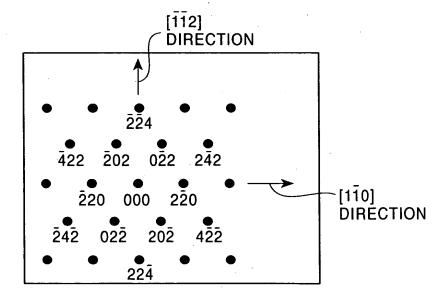




FIG. 24

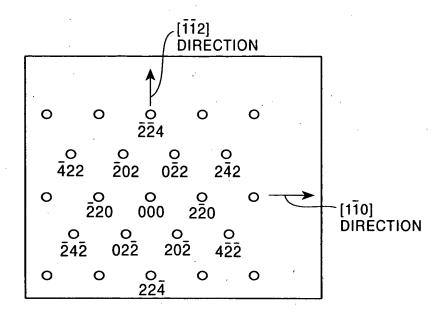
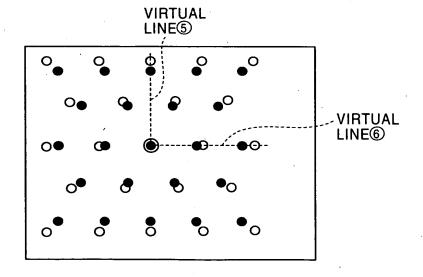


FIG. 25



nge Coupling Film and Magnetoresistive Elemy
Using the Same
Naoya Hasegawa et al.
Attorney Docket No. 9281-3995

 $17 \angle 20$

FIG. 26

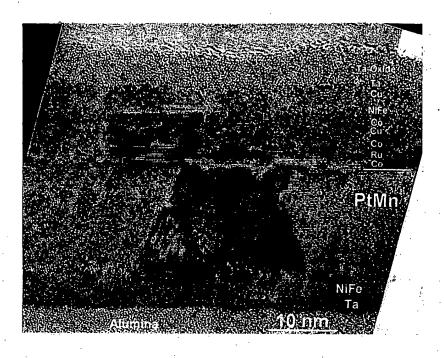


FIG. 27

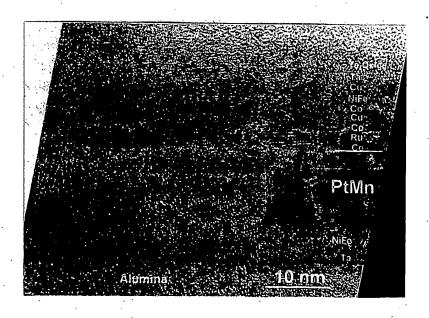


FIG. 28

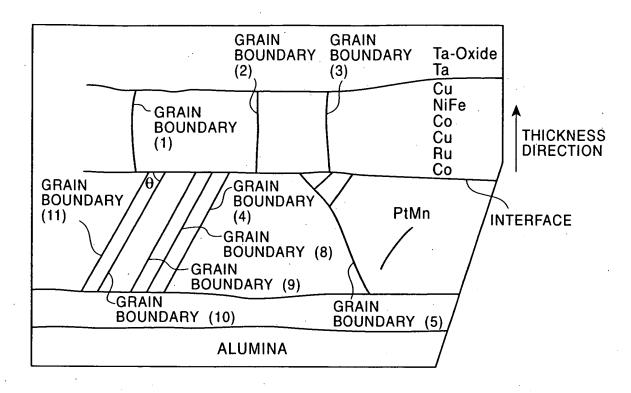
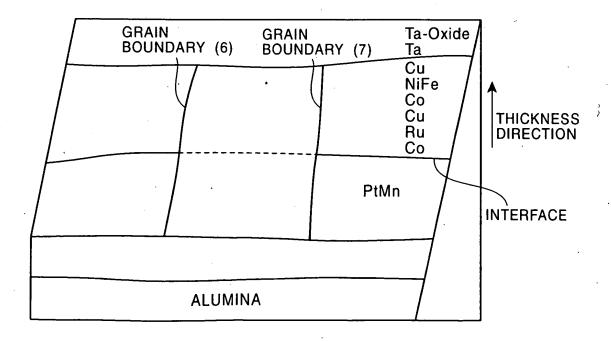


FIG. 29



ge Coupling Film and Magnetoresistive Element Using the Same Naoya Hasegawa et al. Attorney Docket No. 9281-3995

19 / 20

FIG. 30

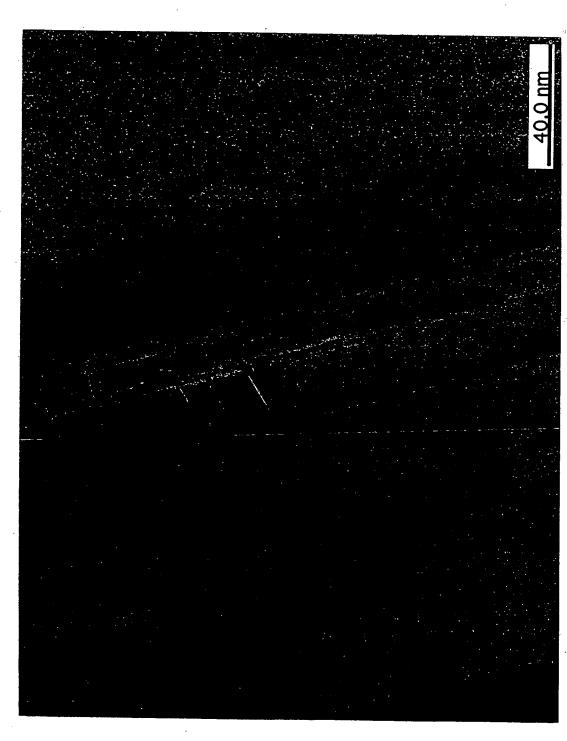




FIG. 31

